HIDEN ANALYTICAL

instruments for advanced science

30 Years

O2/Ar Ion Gun Spots the Difference

The Hiden IG20 high-brightness gas ion gun is further enhanced by the introduction of a new beam optic and ion source configuration to enable both increased beam brightness AND beam contrast, together with a significant reduction in ultimate spot size.

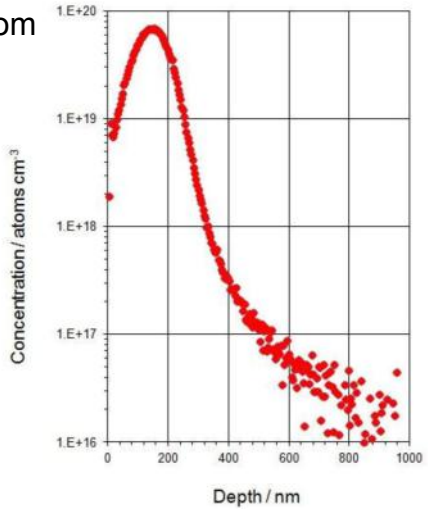
With a raster scanning area of 4x4mm the IG20 is equally suited to depth profiling and to surface imaging applications, and is the preferred gas ion gun for secondary ion and secondary neutral mass spectrometry, for Auger and for XPS. Parameter selection and gun operation are fully under PC control, and the gun is operable with both oxygen and with inert gas primary sources.

Two interchangeable ion sources are available for operation with the same beam optic configuration. One is optimized for general analysis with maximum brightness and a beam current of 800nA, one is optimized for high dynamic range depth profiling applications with minimized beam scatter and supporting a beam current of 200nA within a beam diameter of just 80 micron.

The IG20 ion gun is differentially pumped and includes full raster scanning, incorporation of a neutrals dump, DN-35-CF(2.75 inch diameter) Conflat-type mounting flange and simple replacement of the ion source yttria-coated iridium twin-filament. Companion products include the IG-5C metal ion gun with caesium source and a choice of quadrupole SIMS detectors

For further information on this or other Hiden Analytical products contact Hiden Analytical Inc. at info@hideninc.com or visit the main website at www.HidenInc.com

IG20 5 KeV Argon or Oxygen ion source for UHV surface analysis applications



1E15 atoms cm^{-3} 24 Mg implant in silicon analyzed with 5 keV O_2+ primary ions